

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Attorney Docket No. 50169/105

In re patent application of

Wallace T.Y. TANG

Serial No. 08/401,229

Filed: March 9, 1995

Group Art Unit: 2874

Examiner: J. Lee

For: IN-SITU REAL-TIME MONITORING TECHNIQUE AND APPARATUS FOR ENDPOINT  
DETECTION OF THIN FILMS DURING CHEMICAL/MECHANICAL POLISHING  
PLANARIZATION

TRANSMITTAL

RECEIVED

AUG 20 1998

GROUP 2200

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Transmitted herewith is an Amendment in the above-captioned application.  
The fee has been calculated as shown below. (Small entity fees indicated  
in parentheses.)

CLAIMS AS AMENDED						
(1)	(2)	(3)	(4)	(5)	(6)	(7)
	Claims Remaining After Amendment		Highest Number Previously Paid For	Extra Claims	Rate	Fee
Total Claims (Small Entity)	100	-	67	33	22.00 (11.00)	363.00
Independent claims (Small Entity)	14	-	14	0	80.00 (40.00)	0.00
Multiple Dependent (Small Entity)		-			260.00 (130.00)	
Extension of Time	One Month		Two Months	Three Months		
Fee	\$110		\$390	\$930		
(Small Entity)	(\$55)		(\$195)	(\$465)		
Total						\$363.00

A check in the amount of the above Total Fee is attached. This amount is  
believed to be correct; however, the Commissioner is hereby authorized to  
charge any deficiency or credit any overpayment to Deposit Account No. 19-  
0741.

Respectfully submitted,

Date: August 20, 1998



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#22/Amend G1  
J. Hood  
9-4-98

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Attorney Docket No. 50169/105/ENPO

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Wallace T.Y. TANG

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entry  
approved  
JDL  
10/16/98

SUPPLEMENTAL AMENDMENT AFTER FINAL REJECTION  
AND REQUEST FOR RECONSIDERATION  
UNDER 37 C.F.R. § 1.116

Assistant Commissioner for Patents  
Washington, D.C. 20231

Sir:

Supplemental to the amendment filed on July 28, 1997 and  
in further response to the outstanding Office Action mailed on  
April 28, 1997, please amend the above-identified application as  
follows:

IN THE CLAIMS

Please cancel claims 48<sup>✓</sup>-52, 61<sup>✓</sup>-73, 75<sup>✓</sup>, 79<sup>✓</sup>-90 without  
prejudice or disclaimer to the subject matter.

08/21/1998 JPROCTOR 00000004 08401229

01 FC:203

363.00 OP

Please add the following claims:

40  
-- 1. A chemical mechanical polisher for polishing a  
film over a substrate comprising

G1  
at least one light source capable of transmitting  
light through a rotatable polishing pad to the film;

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